

AUG 25 2003  
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 PATENT & TRADEMARK OFFICE

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Wen-Ben CHOU et al.

Application No: 09/998,858

Filed: October 31, 2001

For: METHOD AND APPARATUS FOR NITRIDE  
 SPACER ETCH PROCESS IMPLEMENTING -  
 IN SITU INTERFEROMETRY ENDPOINT  
 DETECTION AND NON-INTERFEROMETRY  
 ENDPOINT MONITORING

Attorney Docket No: LAM2P295

Examiner: Chen, Kin Chan

Group Art Unit: 1765

Date: August 19, 2003

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CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to: Commissioner for Patents, Alexandria, VA 22313-1450 on August 19, 2003.

Signed:   
 Courtney F. Yadegar

Commissioner for Patents  
 Alexandria, VA 22313-1450


Sir:

Transmitted herewith is an Amendment in the above-identified Application.

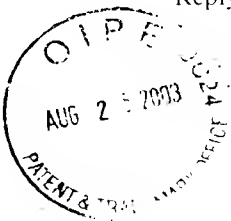
The fee has been calculated as shown below.

	Claims Remaining After Amendment	Highest Previously Paid For	Present Extra	SMALL ENTITY RATE FEE	OR	LARGE ENTITY RATE FEE
TOTAL CLAIMS	16	20	00	X09 = \$	OR	X18 = \$
INDEP CLAIMS	04	03	1	X42 = \$	OR	X84 = \$84.00
[ ] Multiple Dependent Claim Present and Fee Not Previously Paid				S140		\$280
TOTAL				\$		\$84.00

- ☐ Applicant(s) hereby petition for a \_\_\_\_\_ month(s) extension of time to respond to the outstanding Office Action.
- ☒ Applicant(s) believe that no (additional) Extension of Time is required; however, if it is determined that such an extension is required, Applicant(s) hereby petition that such an extension be granted and authorize the Commissioner to charge the required fees for an Extension of Time under 37 CFR 1.136 to Deposit Account No. 50-0805.
- ☐ Enclosed is our Check No. \_\_\_\_\_ in the amount of \$ \_\_\_\_\_ to cover the additional claim fee and/or extension of time fees.
- ☒ Please charge one claim fee of \$84.00 to Deposit Account 50-0805 (Order No. LAM2P295). Also, If the required fees are missing or any additional fees are required to facilitate filing the enclosed response, please charge such fees or credit any overpayment to Deposit Account No. 50-0805 (Order No. LAM2P295). A copy of this sheet is enclosed.

Respectfully submitted,  
 MARTINE & PENILLA LLP  
  
 Fariba Yadegar-Bandari, Esq.  
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Signed: \_\_\_\_\_

Courtney F. Yadegar

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

AMENDMENT

Dear Sir:

In response to the Office Action mailed on May 19, 2003, please enter the following amendments and remarks in the above-identified patent application:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims, which begins on page 4 of this paper.

Remarks/Arguments begin on page 9 of this paper.